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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (use as many sheets as necessary)				Application Number	10/710,012
				Filing Date	June 11, 2004
				Applicant(s)	Chien-Chao Huang, et al.
				Art Unit	2811 2812
				Examiner Name	Isabe
SHEET	1	OF	1	Attorney Docket Number	2001.1531 / 24061.439

U. S. PATENT DOCUMENTS				
Examiner's Initials	Cite No.	Document Number	Publication Date	Name of Patentee or Applicant of Cited Document
SDF	AA	5,516,724	05-14-1996	Ast, et al.
	AB	5,624,869	04-29-1997	Agnello, et al.
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OTHER PRIOR ART				
Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume, issue number(s), publisher, city, country, where published		
SDF	AH	GLUCK, M., et al., "CoSi <sub>2</sub> and TiSi <sub>2</sub> for Si/SiGe Heterodevices", Elsevier Science S.A., Thin Solid Films 270, 1995, pages 549-554.		
	AI	KRIVOKAPIC, Z, et al., "Nickel Silicide Metal Gate FDSOI Devices with Improved Gate Oxide Leakage", IEEE, 2002, 0-7803-7469-X/02, 4 pages.		
	AJ	NAYAK, D. K., et al., "Enhancement-Mode Quantum-Well Ge <sub>x</sub> Si <sub>1-x</sub> PMOS, IEEE Electron Device Letters, Vol. 12, No. 4, April 1991, pages 154-156.		
	AK	XIANG, QI, et al., "Strained Silicon NMOS with Nickel-Silicide Metal Gate", 2003 Symposium on VLSI Technology Digest of Technical Papers, 4-89114-035-6/03, 2 pages.		
	AL	YEO, YEE-CHIA, et al, "Enhanced Performance in Sub-100 nm CMOSFETs Using Strained Epitaxial Silicon-Germanium", IEDM, pages 753-756.		

Examiner Signature	<i>Staneta Lave</i>	Date Considered	9/18/05
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.